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(12) **United States Design Patent**  
**Murata et al.**

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(54) **HEATER FOR SEMICONDUCTOR  
THERMAL PROCESS**

C23C 16/481; C30B 13/20; H05B 6/36;  
H05B 6/362; H05B 6/44

See application file for complete search history.

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(\*\*) Term: **15 Years**

(Continued)

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(30) **Foreign Application Priority Data**

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(51) **LOC (10) Cl.** ..... **13-03**

(52) **U.S. Cl.**  
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(58) **Field of Classification Search**

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D30/151, 152; D11/130; 414/935-941,  
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219/385, 624, 630, 638

CPC ... H01L 21/67; H01L 21/67011; H01L 21/02;  
H01L 21/02002; H01L 21/67098; H01L  
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H01L 23/345; H01L 23/3677; C23C  
16/4586; C23C 16/46; C23C 16/466;

(57) **CLAIM**

The ornamental design for a heater for semiconductor thermal process, as shown and described.

**DESCRIPTION**

FIG. 1 is a front, bottom, right side perspective view of a heater for semiconductor thermal process showing our new design;

FIG. 2 is a front elevational view thereof;

FIG. 3 is a rear elevational view thereof;

FIG. 4 is a left side elevational view thereof;

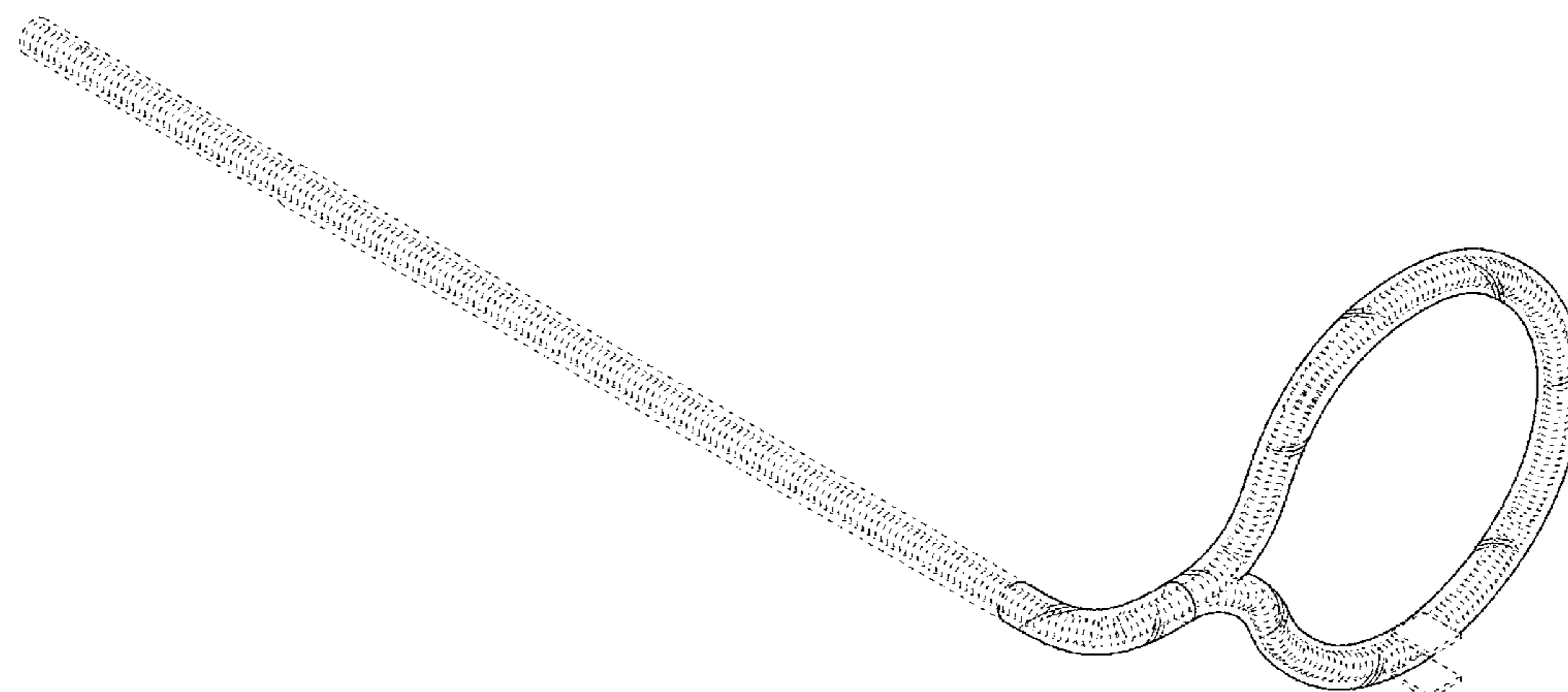
FIG. 5 is a right side elevational view thereof;

FIG. 6 is a top plan view thereof; and,

FIG. 7 is a bottom plan view thereof.

The dashed-dot-dashed lines represent the boundary lines of the claimed design.

(Continued)



The broken lines shown in the drawings represent portions of the heater for semiconductor thermal process that form no part of the claimed design.

**1 Claim, 5 Drawing Sheets**

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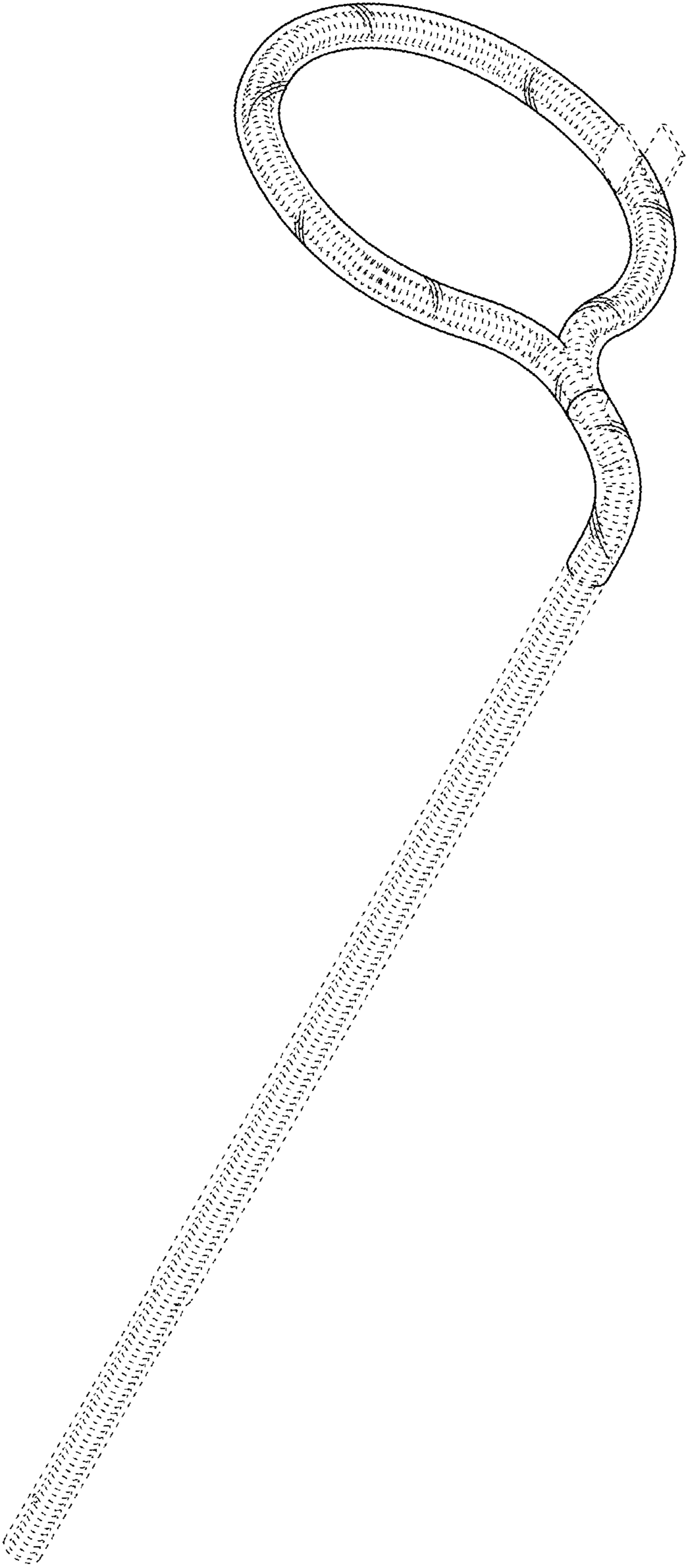


FIG. 1



FIG. 2



FIG. 3

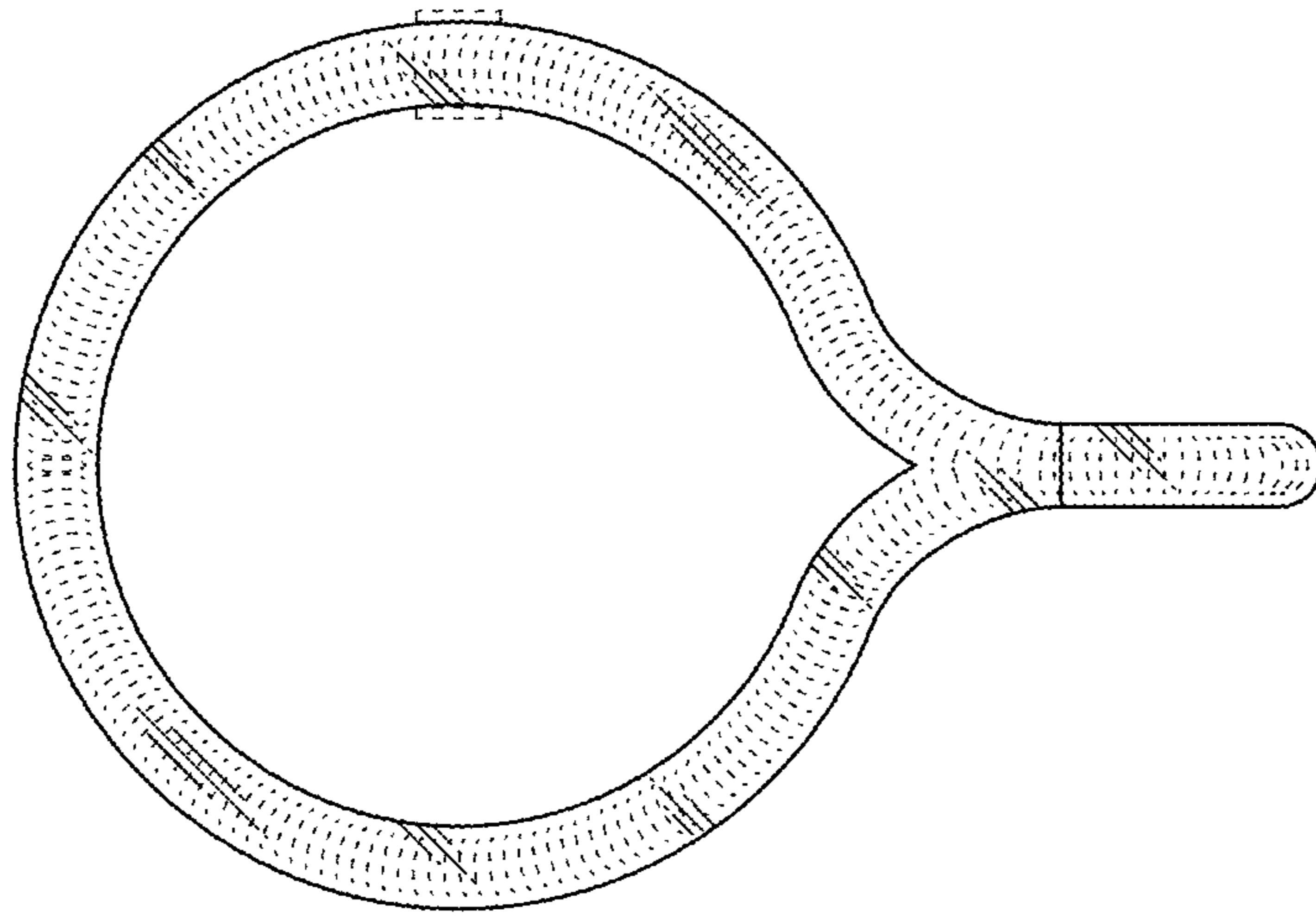


FIG. 5

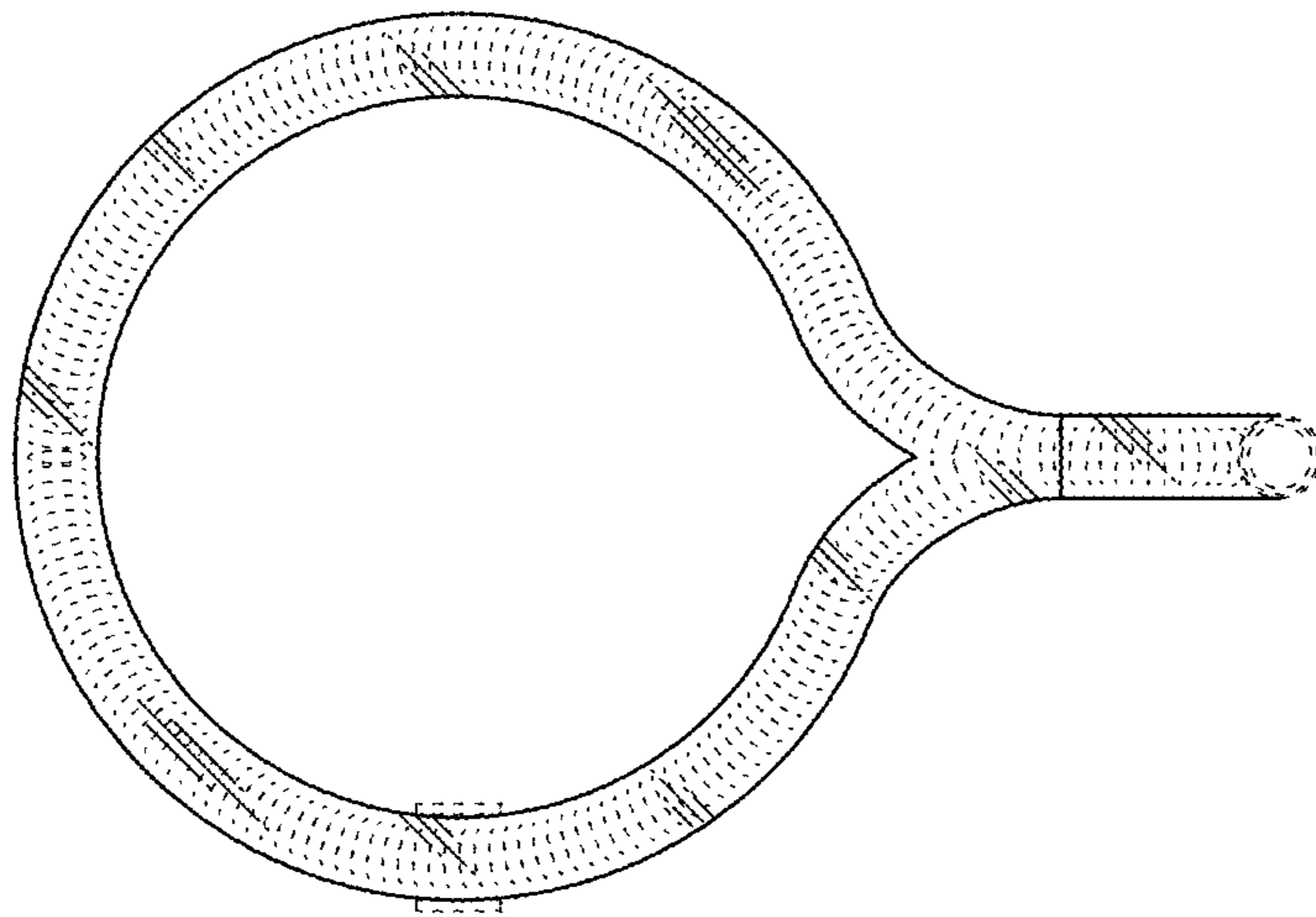


FIG. 4

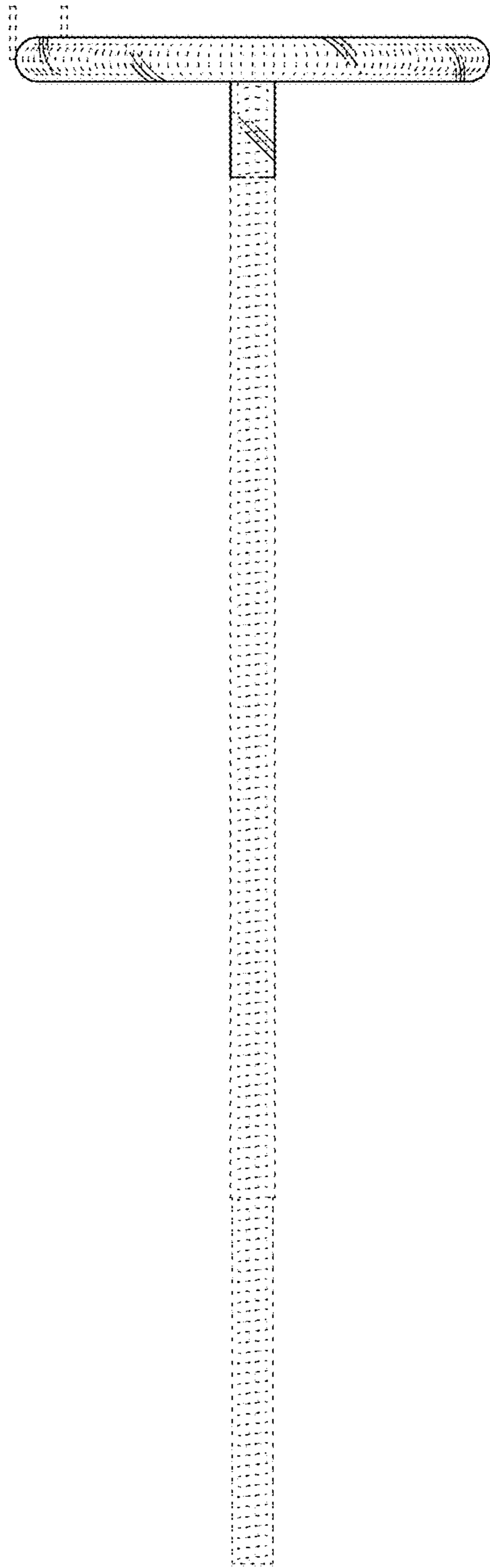


FIG. 6

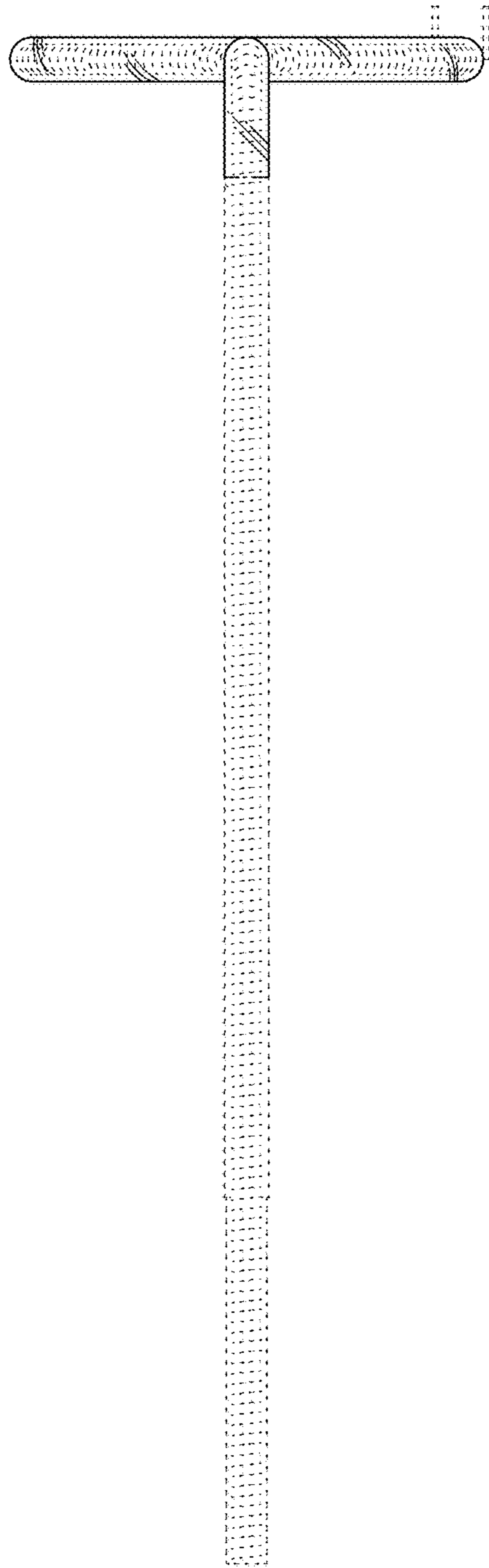


FIG. 7